Multiple-wavelength vertical-cavity laser arrays based on postgrowth lateral-vertical oxidation of AlGaAs

Citation for published version (APA):

DOI:
10.1063/1.121795

Document status and date:
Published: 01/01/1998

Document Version:
Publisher’s PDF, also known as Version of Record (includes final page, issue and volume numbers)

Please check the document version of this publication:
• A submitted manuscript is the version of the article upon submission and before peer-review. There can be important differences between the submitted version and the official published version of record. People interested in the research are advised to contact the author for the final version of the publication, or visit the DOI to the publisher's website.
• The final author version and the galley proof are versions of the publication after peer review.
• The final published version features the final layout of the paper including the volume, issue and page numbers.

Link to publication

General rights
Copyright and moral rights for the publications made accessible in the public portal are retained by the authors and/or other copyright owners and it is a condition of accessing publications that users recognise and abide by the legal requirements associated with these rights.

• Users may download and print one copy of any publication from the public portal for the purpose of private study or research.
• You may not further distribute the material or use it for any profit-making activity or commercial gain
• You may freely distribute the URL identifying the publication in the public portal.

If the publication is distributed under the terms of Article 25fa of the Dutch Copyright Act, indicated by the “Taverne” license above, please follow below link for the End User Agreement:
www.tue.nl/taverne

Take down policy
If you believe that this document breaches copyright please contact us at:
openaccess@tue.nl
providing details and we will investigate your claim.

Download date: 26. Mar. 2024
Multiple-wavelength vertical-cavity laser arrays based on postgrowth lateral-vertical oxidation of AlGaAs

A. Fiore, a) Y. A. Akulova, J. Ko, E. R. Hegblom, and L. A. Coldren

Department of ECE, University of California at Santa Barbara, Santa Barbara, California 93106

(Received 6 March 1998; accepted for publication 15 May 1998)

We demonstrate that combined lateral-vertical oxidation of AlGaAs can be used to change the resonant wavelength of an optical cavity after the single epitaxial growth. A multiple-wavelength array of vertical-cavity surface-emitting lasers with a 48 nm wavelength span has been realized using this technique. © 1998 American Institute of Physics. [S0003-6951(98)02929-5]

Multiple-wavelength arrays of lasers and detectors are required for wavelength division multiplexing (WDM) systems. Vertical-cavity surface-emitting lasers (VCSELs) on GaAs substrates are ideally suited as sources in short-haul WDM systems, as densely-packed 2D arrays of surface emitters can be fabricated. Recently, a compact, "pie-shaped" array of VCSELs direct coupled to a single multimode fiber has been demonstrated.1 This opens the way to WDM communication between multiple-wavelength arrays of emitters and detectors coupled to the same fiber.1,2 However, realization of these arrays requires a good control of the lasing wavelength over small areas of the epitaxial wafer.3 The tuning range is therefore centered at λ=951 nm when the Al0.7Ga0.3As is vertically oxidized by 95 nm. The change in the resonant wavelength of an optical cavity after the single epitaxial growth. A multiple-wavelength array of vertical-cavity surface-emitting lasers with a 48 nm wavelength span has been realized using this technique.

FIG. 1. Schematics (not to scale) of wavelength tuning in a VCSEL by using lateral-vertical oxidation. The water vapor is supplied to the tuning layer inside the cavity by the lateral oxidation of the supply layer.
951 nm. The active region consists of three 80 nm In$_{0.18}$Ga$_{0.82}$As/GaAs quantum wells at the center of an Al$_{0.98}$Ga$_{0.02}$As 1 $\lambda$ cavity. The room-temperature photoluminescence peak is centered at 976 nm. The electrical pumping is provided by two intracavity contacts, realized on a bottom Si-doped (2 x 10$^{18}$ cm$^{-3}$) 3/4 $\lambda$ GaAs $n$-contact layer and a top Be-doped (2 x 10$^{18}$ cm$^{-3}$) 3/4 $\lambda$ p-GaAs contact layer. The lateral current confinement is provided by the oxidation of a 27 nm thick Al$_{0.98}$Ga$_{0.02}$As aperture layer between the active region and the top $p$-contact. In our simulations, the uniformity of threshold current density is limited by the bandwidth of the top DBR mirror if a semiconductor mirror is used. To achieve a large lasing wavelength span, we use a top mirror composed of two periods of GaAs/(Al oxide) Bragg pairs, next to the cavity, and 8 periods of GaAs/Al$_{0.9}$Ga$_{0.1}$As Bragg pairs. The high index contrast GaAs/(Al oxide) periods increase the total tuning range and the mirror bandwidth to a point where the uniformity of threshold current density is likely to be limited by the gain bandwidth. Figure 2 shows the calculated wavelength shift (with respect to $\lambda$ = 951 nm) and corresponding threshold gain, as a function of the vertically oxidized thickness $t_{\text{oxide}}$ ($t_{\text{oxide}}$ = 0 corresponds to the situation where only the 83 nm thick AlAs supply layer is oxidized). We assume a 12% contraction of both AlGaAs and AlAs upon oxidation. For $t_{\text{oxide}}$ > 150 nm, two modes in the cavity compete for threshold (upper and lower branch of the continuous line). The resulting lasing wavelength will be determined by the optical loss of the modes and their spatial overlap with the gain region (i.e., the enhancement factor) and by their spectral overlap with the gain spectrum.

Device fabrication comprises multiple etching steps to expose the intracavity contacts and the layers to be oxidized, two separate oxidation steps, and finally, contact deposition. Etches are realized by Cl$_2$ reactive ion etching. First, circular mesas of varying diameters on a 250 $\mu$m pitch are defined by etching through the top DBR down to the $p$-contact layer. Larger mesas, aligned to the existing ones, are then etched down to the $n$-contact layer. A 240 nm thick layer of SiN$_x$ is then deposited by plasma-enhanced chemical vapor deposition at 350 °C. This is needed to prevent oxidation of the aperture layer during the oxidation of the tuning layer. Stripes with varying widths ($W = 60, 65, 70, 76, 83, 91, 100, 111, 123, 139, 164, 200 \mu$m), centered on the mesas, are defined by etching into the bottom DBR. These stripes are used as a pattern for lateral oxidation of the AlAs supply layer. The oxidation is performed at 465 °C for 40 min in a water-vapor atmosphere obtained by bubbling $N_2$ through water at 80 °C. SiN$_x$ is then removed by CF$_4$ plasma etching and the sample is oxidized again at 435 °C for 16 min. During this time, the two AlAs layers in the top DBR are completely oxidized, whereas oxidation of the aperture leaves a channel (6–8 $\mu$m diameter) for current flow into the active region. $p$-metal (Au–Zn–Au) and $n$-metal (Ni–Ge–Au–Ni–Au) are then evaporated on the corresponding contact layers. In order to avoid thermal stress in thick oxide layers, the contacts were not annealed.

The devices were tested at room temperature under dc electrical pumping. Figure 3 shows lasing spectra from devices having different stripe widths. The peaks are numbered corresponding to the stripe width, No. 1 being the smallest ($W = 60 \mu$m), No. 12 the largest ($W = 200 \mu$m). Figure 4 shows the net wavelength shift (filled dots, with respect to the central wavelength, $\lambda = 951$ nm), as a function of the stripe width. A small gradient in resonant wavelength (1 nm/
device), due to a gradient in growth rate, has been subtracted to give the net tuning due to oxidation. On the right axis the corresponding oxidized thickness $t_{\text{oxide}}$ is shown (empty squares), as deduced from the wavelength shift using the tuning curve on Fig. 2. Moving from larger to smaller stripe widths, the tuning layer becomes more and more oxidized, and the lasing wavelength decreases accordingly. For $t_{\text{oxide}} > 130$ nm, the devices start lasing on the longer wavelength mode, which is closer to the gain peak. A net 48 nm span is obtained by exploiting the two lasing modes. An even larger lasing span can be obtained by placing the gain peak at the center of the tuning range. Figure 4 shows that the oxidized thickness $t_{\text{oxide}}$ varies nonlinearly with the stripe width. This nonlinear dependence is related to the spatial distribution of the oxidizing species in the supply and tuning layers and will be the object of further investigation. The nonlinear stripe width sequence used in the experiment partially compensates for this nonlinearity and allows to exploit all the available wavelength span.

The inset in Fig. 3 shows the threshold current as a function of the wavelength. All devices have 8 $\mu$m diameter current apertures, except those emitting at 959, 984, and 990 nm, which have 6 $\mu$m diameters. Due to processing problems, a gold layer was left on the top of the pillar on some of the devices. Although still lasing (with output from the bottom DBR), these devices present higher threshold currents (empty squares). The other, top-emitting lasers (filled dots) have sub-mA threshold currents in the 960–990 nm range. The corresponding threshold voltages are in the 4–6 V range and differential efficiencies vary between 10 and 30%. We attribute these high voltages to the voltage drop in the nonannealed contacts. The variation in threshold currents and differential efficiencies is likely to be due to non-optimized device processing.

In conclusion, we have demonstrated a new approach to multiple-wavelength VCSEL arrays. It is based on post-growth lateral-vertical oxidation of an intracavity AlGaAs layer. Contrary to techniques based on anodic oxidation or growth on patterned substrates, this technique uses a single epitaxial growth on conventional substrates, which results in easier device fabrication. We have measured a 48 nm lasing wavelength span. This method is very flexible and should lead to low-cost fabrication of densely-packed WDM arrays of lasers and detectors.

The authors wish to thank Dr. Oded Buchinsky, Dr. Syen-Yen Hu, and Dr. Ola Sjolund for useful discussions. This work was supported by AFOSR and DARPA.